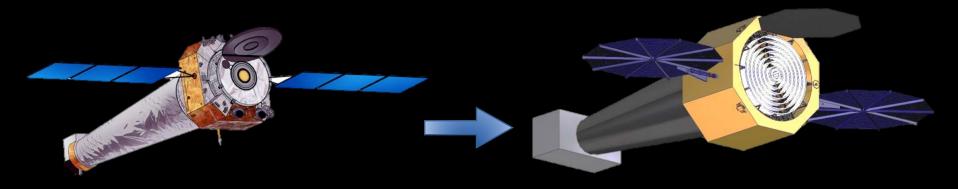
Adaptive X-ray Optics IV (SPIE 9965) 2016 August 28; San Diego, CA (USA)

Toward large-area sub-arcsecond x-ray telescopes II



Chandra X-ray Observatory (1999-?)

X-Ray Surveyor concept (~2035?)

Steve O'Dell

NASA Marshall Space Flight Center

and co-authors

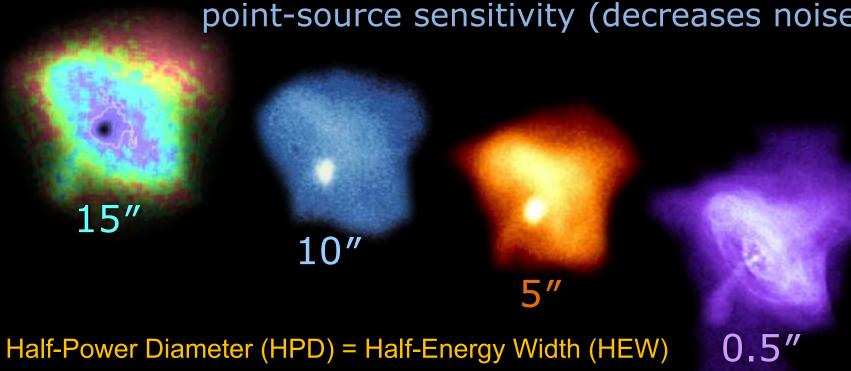
Authors represent most of the US effort toward sub-arcsecond x-ray telescopes.

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Key science metrics of an x-ray telescope are angular resolution and aperture area.

Finer angular resolution improves imaging quality and point-source sensitivity (decreases noise).



Larger aperture area improves sensitivity (increases signal), down to angular-resolution confusion limit.

Outline

- Motivation and issues
- Categories of potential solutions
- Post-fabrication corrections

Outline

- Motivation and issues
 - □ Seek Chandra resolution with 30 × Chandra area.
 - Must resolve both technologic and programmatic challenges.
 - Achieve aperture area and imaging performance within constraints of mass, envelope, cost, and schedule.
- Categories of potential solutions
- Post-fabrication corrections

2020 Decadal Survey in Astronomy and Astrophysics sets priorities for decade.

- National Research Council (NRC) conducts Survey for relevant Government agencies (NASA & NSF).
 - □ Addresses space-based and ground-based astronomy.
 - NASA typically adopts Decadal Survey's priorities.
 - □ NASA will suggest space-based astronomy missions.
 - Four Science and Technology Definition Teams (STDT) are developing facility-class mission concepts for NASA.
 - X-Ray Surveyor
 - Far-IR Surveyor
 - LUVOIR Surveyor
 - Habitable Exoplanet Imaging (HabEx)
 - Only one of these is likely to start in the 2020s.
 - Expected launch date would be mid-to-late 2030s.

STDT is defining science-driven requirements for X-Ray Surveyor.

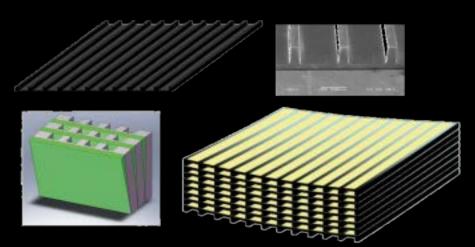
- Anticipate scientific need for an x-ray telescope with Chandra's 0.5" resolution and 30 x its area.
- There is general agreement on the top-level technologic and programmatic challenges.
 - □ Preserve *Chandra's* angular resolution ≈ 0.5" HPD.
 - □ Reduce mirror areal mass to Chandra/30 $\approx 1.5 \text{ kg/m}^2$.
 - □ Reduce mirror areal cost to Chandra/30 \approx 1 M\$/m².
- There is not general agreement on how to solve these challenges.
 - Stiff optics (rigidly supported over-constrained mirrors)
 - Static optics (fixed, moderately constrained mirrors)
 - □ Active optics (adjustable alignment | figure correction)

Outline

- Motivation and issues
- Categories of potential solutions
 - □ Stiff optics
 - □ Static optics
 - □ Active optics
- Post-fabrication corrections

ESA selected ATHENA as its 2nd large-class (L2) mission, for launch in 2028.

- X-ray mission is in study Phase A, working toward adoption around 2020.
 - □ Require HEW ≈ 5 ".
- ATHENA will use stiff, silicon-pore optics (SPO).
 - Cosine MeasurementSystems [NL] leads SPOtechnology development.
 - Processing and stacking of silicon wafers are highly automated.
 - Resulting rigid x-ray optics units are to be co-aligned.

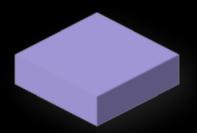




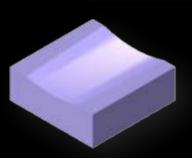
ESA/ Marcos Bavdaz

<u>www.the-athena-x-ray-observatory.eu</u>

GSFC uses a novel process for light x-ray mirrors of monocrystalline silicon.



- 1. Procure single crystalline silicon.
- 2. Heat and chemically etch to remove all surface/subsurface damage.



- 1. Wire-EDM machine conical shape.
- 2. Heat and chemically etch to remove damage.
- 3. Polish to achieve excellent figure and micro-roughness.



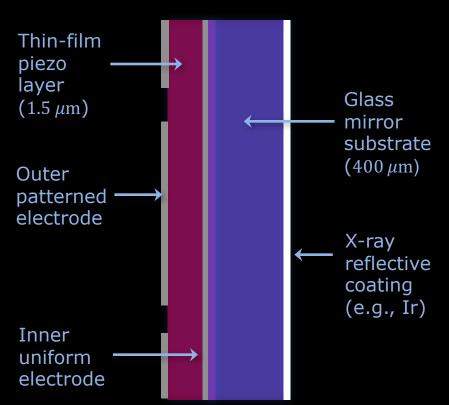
- 1. Use Wire-EDM to slice off the thin mirror segment.
- 2. Heat and chemically etch to remove all damage from back and edges.

- Advantages over glass
 - No internal stress
 - Distortion-free material removal after etching
 - □ Ideal material properties
 - High thermal conductivity
 - Low thermal expansion
 - High elastic modulus
 - Better performance
 - Made mirrors < 3" HEW₂
 - Aim to build ~ 1" mirror stack by end 2017
 - Aim to build ~ ≥.;1" metashell by end 2019.

GSFC/ Will Zhang

SAO is developing lightweight active x-ray optics with thin-film piezo arrays.

 Piezoelectric array corrects figure through surface-parallel actuation

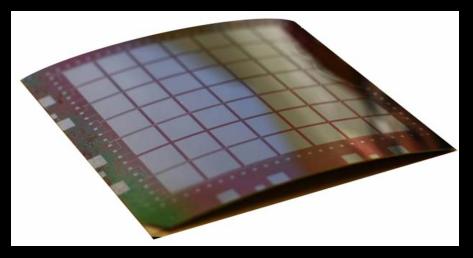


- PSU is fabricating thinfilm piezoelectric arrays.
 - □ Slumped-glass mirrors from SAO (OAB)
 - □ Piezoelectric (PZT) on conductive film, high-T crystallized and annealed
 - Patterned electrode array with ZnO TFTs
 - Row-column addressing
 - Anisotropic Conductive Film (ACF) connections
 - Integral T-compensated strain gauges

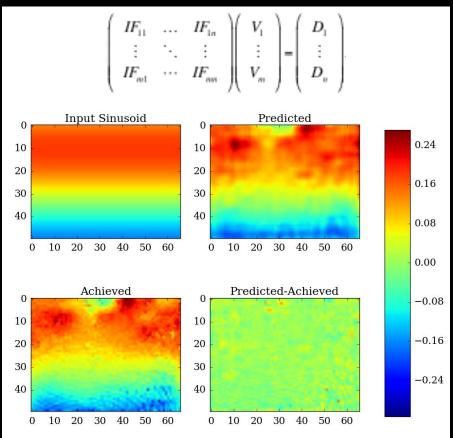
SAO/ Paul Reid

Correction uses calibrated influence functions to determine array voltages.

- Adjustment methodology
 - Shack-Hartman wavefront sensor metrology
 - Calibrate influence function
 - Measure mirror figure
 - Calculate and apply voltages for correction



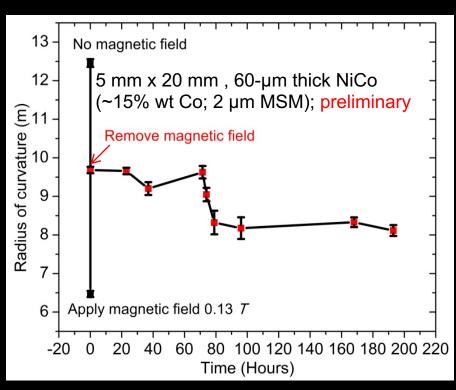
Correction matrix



SAO/ Ryan Allured

A magnetic smart material MSM provides writable surface-parallel actuation.

- Use a magnetically hard substrate or coated layer.
- Deposit magnetostrictive (MSM) thin film on back.

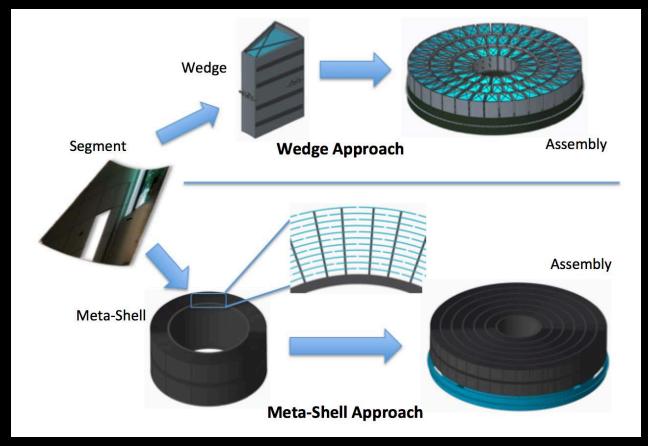


- Northwestern Univ. is developing MSM actuators for x-ray optics.
 - Demonstrated that concept may work.
 - Must speed up relaxation and stabilization.
 - Are building models to compare to experiments.
- Can also control coating stress to provide some static figure correction.

NWU/ Mel Ulmer NWU/ Xiaoli Wang

Synthesize large-area nested Wolter-1-like telescope with aligned segments.

> Few-100-m² surface area in several 1000 segments



GSFC/ Will Zhang

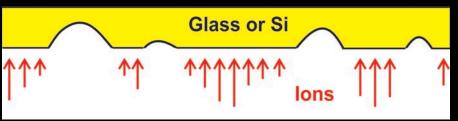
Outline

- Motivation and issues
- Categories of potential solutions
- Post-fabrication corrections
 - Differential erosion or deposition
 - Coating stress manipulation
 - □ Ion implantation

Low-pressure subtractive or additive machining corrects residual figure errors.

Differential Erosion

Differential Deposition



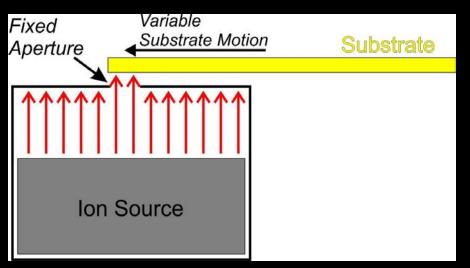
Glass or Si

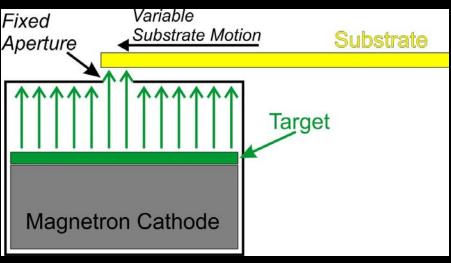
Coating

Atoms ATT Atoms

Ion-Beam Figuring

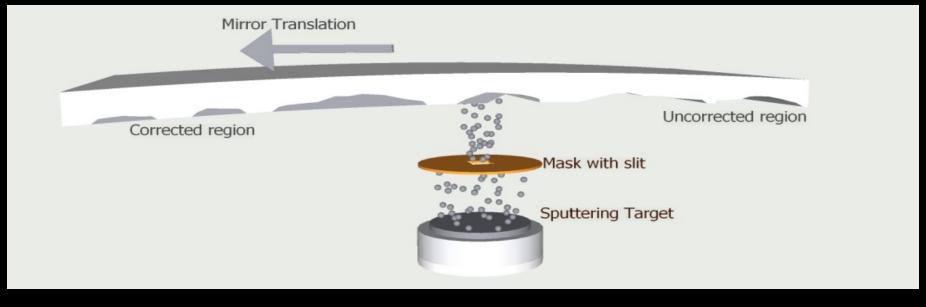
Selective Deposition

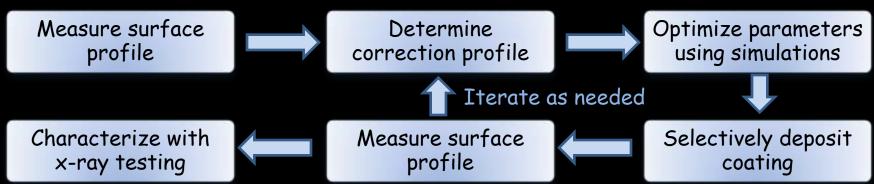




RXO/ David Windt

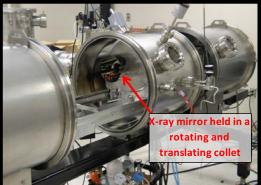
Differential deposition allows correction of mid-frequency figure errors.





MSFC/USRA/ Kiran Kilaru

MSFC is applying differential deposition to correct thin-walled x-ray mirrors.





Horizontal differential-deposition chamber

- Results are promising.
 - 2-pass correction of HEW by factor of 3 (metrology)
 - □ 1-pass correction of HEW by factor of 2 (x-ray test)
 - 3 corrected azimuthal sections in intrafocal image

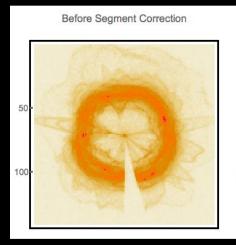


Metrology of shell with MSFC VLTP and circularity test stand



positioned inside shell

Corrected shell installed in bell housing for x-ray testing at MSFC 100-m beam



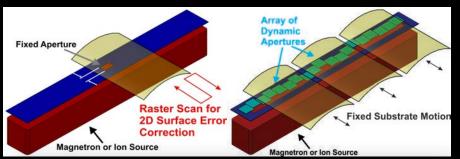
After 1st Segment Correction Iteration

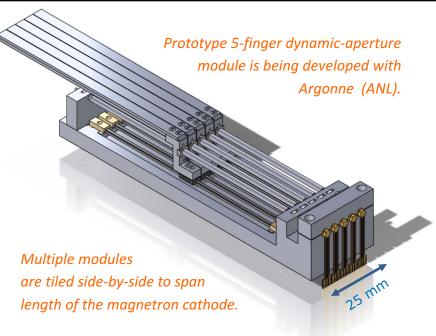
Corrected Segments; Measured Segments

50

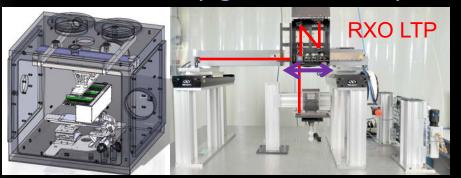
MSFC/USRA/ Kiran Kilaru

RXO is developing dynamic apertures for 2D differential erosion or deposition.





- Dynamic aperture array
 - Simultaneously corrects multiple azimuths
 - Constant axial speed
 - Modulated aperture widths
 - Applications
 - o Differential erosion
 - Differential deposition
 - Laterally graded multilayer



RXO/ David Windt

Coating stress is an issue for subarcsecond imaging with thin mirrors.

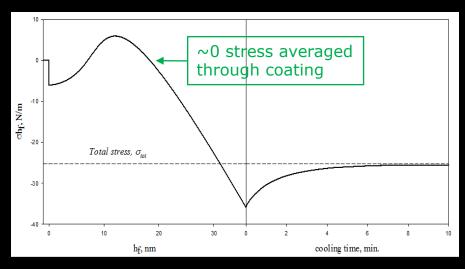
- Astronomical x-ray mirrors use thin-film coatings.
 - □ High-density coating or multilayers for x-ray reflectivity
 - □ For active optics, piezoelectric array
- > Distortion depends upon film stress σ_f and thickness h_f and upon substrate thickness h_s .
 - \square E.g., Stoney formula: $\kappa = 6(1 v_s)\sigma_f h_f/(E_s h_s^2)$
 - \circ Dependence upon substrate thickness h_s is quadratic.
 - \circ Key coating parameter is the integrated stress $\sigma_f h_f$.
 - Both intrinsic coating stress and temperaturedependent strain (CTE differences) cause distortion.
 - Separating these two effects can be challenging.
 - Annealing or other relaxation may play a role.

Several groups are investigating various methods for controlling coating stress.

- Monitor integrated stress in situ during sputtering, to take advantage of dynamics of thin-film growth.
 - MSFC/ David Broadway
- Deposit bilayer to tune the net integrated stress of compressive and tensile thin films.
 - □ RXO/ David Windt; SAO/ Suzanne Romaine
- Deposit coating on front and on back to balance integrated stress.
 - □ GSFC/ Kai-Wing Chan
- Anneal coating at elevated temperature to relieve stress.
 - □ GSFC/ Kai-Wing Chan

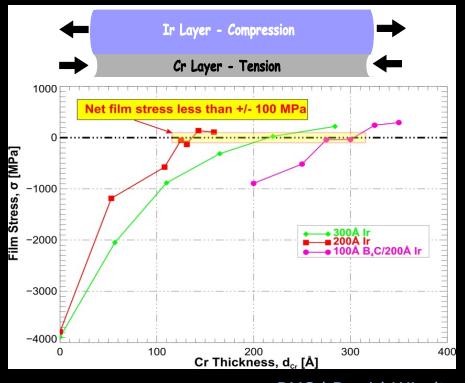
Methods for controlling deposition stress of thin films (continued)

- Iridium film growth
 - Tensile through coalescence stage
 - □ Very compressive after
- > Tune mean stress of film
 - □ -3 MPa, 0.5-nm rough



MSFC/ David Broadway

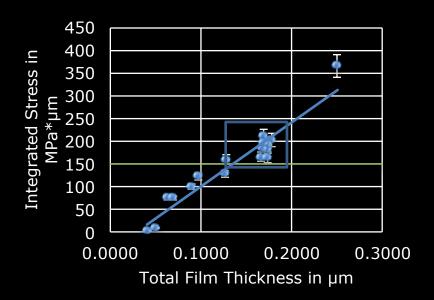
- Bilayer cancelation
 - ☐ Ir compressive stress
 - ☐ Cr tensile stress



RXO/ David Windt

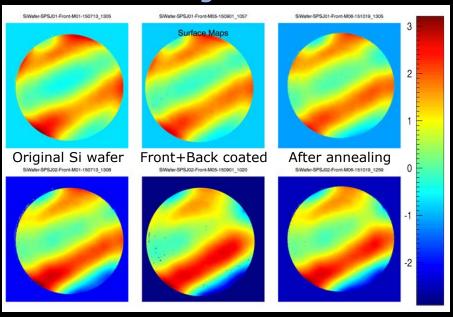
Methods for controlling deposition stress of thin films (continued)

- PZT compensation
 - PZT tensile stress on back
 - □ Ir/Cr bilayer on front
- > Tune net integrated stress
 - □ 10-nm Ir + 160 nm Cr



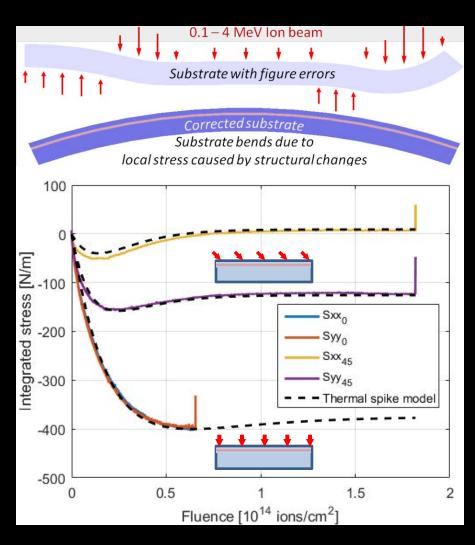
SAO/ Suzanne Romaine

- Multiple approaches
 - □ Front and back coating
 - Sputtering
 - Atomic Layer Deposition
 - □ Annealing at 320°C

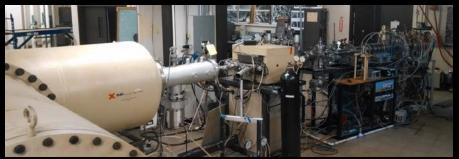


GSFC/ Kai-Wing Chan

Differential stress from ion implantation allows static correction of figure errors.



- MIT is using its ion beam to develop this approach.
 - □ Operates at 1-6 MeV.
 - \circ Implant depth 1 4 μm
 - Low surface degradation
 - ☐ Integrated stress measure
 - Thermal spike model
 - o Anisotropic (∥ vs ⊥) stress
 - Dose-dependent relaxation



MIT/ Brandon Chalifoux

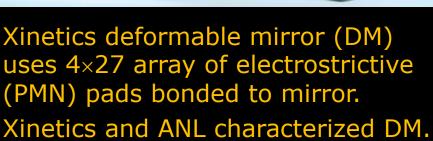
Outline

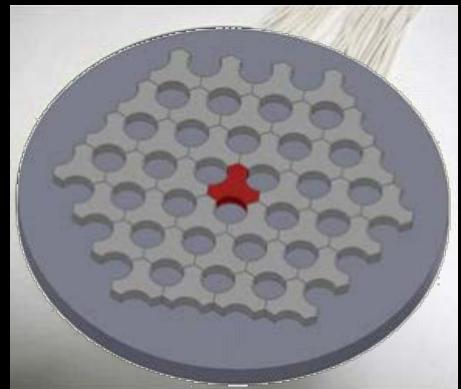
- Motivation and issues
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Back-up slides

An array of electroactive pads provides surface-tangential actuation (STA).







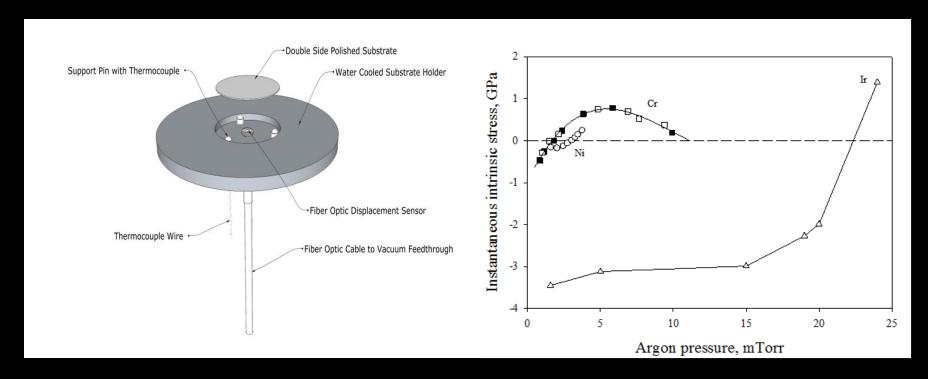
Xinetics prototype uses PMN array bonded to a silicon mirror.

Each node is addressable for STA.

NGC/ AOA Xinetics

MSFC has developed thin-film-stress monitor for in situ measurements.

In-situ measurement helped identify a mechanism for reducing the stress in sputtered iridium by 3 orders of magnitude



MSFC/ David Broadway